10.2 APM CHECKLIST (MTECH TO RETURN COMPLETED CHECKLIST TO MSUP)

MESA Event: _____

Date Started: _____ Time: _____

Time Completed: _____

Engineer Name(s): _____ _____

Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
1.	CsSw_D2dBck.ADJ	Disk To Disk Back Up And Restore	Yes: ____ No: ____	Yes: ____ No: ____
2.	CsFreDskSpa.ADJ	Make More Disk Space	Yes: ____ No: ____	Yes: ____ No: ____
3.	Me5BaSysCor.PER	Pre-PM IQC scan Mag ≤ 0.4 ppm Rotation ≤ 0.4 µrad Translation X ≤ 4 nm Translation Y ≤ 4 nm Image Tilt Rx ≤ 4 µrad Image Tilt Ry ≤ 1.5 µrad Focus ≤ 25 nm	5726 Mag: 0.28 ppm Rotation: 0.03 µRad X: 0.87 nm Y: 0.36 nm Rx: 4.22 µRad Ry: 0.46 µRad Focus: 10.11 nm	Mag: ____ ppm Rotation: ____ µRad X: ____ nm Y: ____ nm Rx: ____ µRad Ry: ____ µRad Focus: ____ nm

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
4.	WhWts.CLE	Clean The Wafer Transport System	Yes: ____ No: ____	Yes: ____ No: ____
5.	WhWps.CLE	Clean The Wafers Prealignment System	Yes: ____ No: ____	Yes: ____ No: ____
6.	WhWtsCal.ADJ	Calibrate The Wafer Transport System	Yes: ____ No: ____	Yes: ____ No: ____
7.	WhWpsCal.ADJ	Calibrate The Wafer Pre-alignment System.	Yes: ____ No: ____	Yes: ____ No: ____
8.	WhWpsMasCal.ADJ	Calibrate The WPS Mark Sensor	Yes: ____ No: ____	Yes: ____ No: ____
9.	ArGui.LUBE	Lubricate Linear Guides And spindles Arms	Yes: ____ No: ____	
10.	ArGri.CLE	Clean The Grippers	Yes: ____ No: ____	
11.	Ar_Lib.CLE	Clean The Libraries	Yes: ____ No: ____	
12.	SrsRetPinChu.CLE	Clean Reticle Support Surfaces Of R-Pins And Reticle Chuck.	Yes: ____ No: ____	
13.	Ct3NpuFil.REP	Remove And Install The NPU Filters	Yes: ____ No: ____	Yes: ____ No: ____
14.	PnPsuCarFil.REP	Remove And Install The PSU ML-1 Carbon Filter.	Yes: ____ No: ____	Yes: ____ No: ____
15.	PnPsuDmpFil.REP	Remove And Install The PSU ML-1 Damp Filter	Yes: ____ No: ____	Yes: ____ No: ____
16.	PnPsuGskFil.REP	Remove And Install The PSU ML-1 Gaskline Filters	Yes: ____ No: ____	Yes: ____ No: ____
17.	CtDonPouFil.REP	Replace The Donaldson POU Air Filter	Yes: ____ No: ____	Yes: ____ No: ____
18.	Pn5Prs.PER	Examine The System Gas And The Air Bearing Gas Pressures.	____Press ure____Bar	____Press ure:____Bar

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		System Gas Pressures 4.5 ± 0.2 bar		
19.	SrsPreVacFlo.PER	Measure Pressures, Vacuums And Flows	Yes: ____ No:	Yes: ____ No:
20.	Pn5Vac.PER	Examine The System Air Bearing Vacuum. Air Bearing Gas Pressure: 6.5 ± 0.2 bar	Pressure: _____ Bar	Pressure: _____ Bar
21.	CtGcuPre.ADJ	Adjust The GCU Gas Pressure. Manometer Reading Visual Check: 100 ± 10 Pa	Pressure: _____ Pa	Pressure: _____ Pa
22.	SwsModAibTsw.DIA	Check SWS Module Air Bearing	Yes: ✓ No: 5/19	
23	Check EMO Circuits (perform only step 9)	DONE?	Y/N	
24	Test the Safety of the Interlocks	DONE?	Y/N	
25.	SrsHpr.ADJ	Check HP Receiver. Adjust HP Receiver	Yes: ____ No: Yes: ____ No:	Yes: _____ No:_____ Yes: ____ No:
26.	SrsLhdIntChk.PER	Check The Intensity Of The Laser Head	Yes: ____ No:	
27.	SwsDynHpRec.Dia	Diagnose The Dynamic HP Interferometer System.	Yes: ✓ No: 3125	
28.	AlaOA_LasPwr.PER	Red OA Alignment-laser Power Output >7 mW Green OA Alignment-laser Power Output > 40 mW	Red: 15.676 mW Green: 45.878 mW	Red: _____ mW Green: _____ mW
29	AlaOA_Att.PER	Alignment Attenuation On Hp N.D.=3, S.D. X and Y. Density=3.0 < 10 nm Alignment Attenuation	Density: _____ nm E-X=15.7 E-Y=15.0	Density: _____ nm

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		On I1p S.D X and Y: orders 3, 5, and 7 for ND=3. Density =3.0 < 10 nm	Density_____ nm RSX = 14.8 RSY = 14.6	Density_____ nm
30.	Ct5Chk.PER	Check CT Performance. Refer to COACH for specifications.	ASML to monitor these parameters.	ASML to monitor these parameters.
31. 7/26/17	I13LasSta.PER	Laser Performance Check	Yes:___ No:___	
32.		Absolute Wavelength Reference Calibration.	Yes:___ No:___	Yes:___ No:___
33.	WhEdgSnsRep251.PER	Edge Sensor Reproducibility 25 x 1: Standard dev. Xalign < 1.5 µm Standard dev. Yalign < 1.5 µm Standard dev. Rot < 30 µrad Mean X align Mean Y align Mean rotation	X: 0.98 µm Y: 1.26 µm Rot: 30.91 µrad Mean X: 13.93 µm Mean Y: 685 µm Mean Rot: -230.59 µrad	X:_____ µm Y:_____ µm Rot_____ µrad Mean X:_____ µm Mean Y:_____ µum Mean Rot:_____ µrad
34.	WhMasRpr251.PER	Mark Sensor Reproducibility 25 x 1: Standard dev. Xalign < 1.5 µm Standard dev. Yalign < 1.5 µm Standard dev. Rot < 30 µrad	X: 0.55 um Y: 2.02 um Rot: 32.04 urad	X:_____ um Y:_____ µm Rot:_____ urad

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Mean X align Mean Y align Mean rotation	Mean X: 8.18 µm Mean Y: -2.90 µm Mean Rot: -79.62 µrad	Mean X: _____ µm Mean Y: _____ µm Mean Rot: _____ µrad
35.	Il5ScaDosAcc.PER	Scanning Dose Repeatability: ≥ 5mj/cm² = ≤ 0.5% Scanning Dose : ≥ 5mj/cm² = ≤ 0.5% Spec. -1< X< 1	Rep 0.11 % Acc: -0.74 %	Rep _____ % Acc: _____ %
36.	Ip2RetMasAcc.PER	Check Reticle Masking Accuracy. Refer to COACH for Specifications	ASML to monitor these parameters.	ASML to monitor these parameters.
37.	TisVerSig.DIA	Test The Transmission Image Sensor Signal	Yes: _____ No:	Yes: _____ No:
38.	TisRep.PER	Measure The Transmission Image Sensor STD Pos x <3 nm STD Pos y <3 nm STD Pos zx < 25.0 nm STD Pos zy < 25 nm Failed Scan = 0	Pos x: 0.88 nm Pos y: 1.52 nm Pos zx: 9.24 nm Pos zy: 9.69 nm Fail 0	Pos x: _____ nm Pos y: _____ nm Pos zx: _____ nm Pos zy: _____ nm Fail _____
39.	MeSBaTaXyFin.ADJ	Fine Set Up Tamis XY ABS (Z7) ≤ 1nm	0.072 nm	_____ nm

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Offset			
		ABS (Z7) Tilt	≤ 1nm	0.238 nm	nm
		ABS (Z8) Offset	≤ 1nm	0.183 nm	nm
40.	Me5BaTaZFin ADJ	Fine Set Up Z9 with Tamis Z. ABS (Z9) Offset ±1.0nm		-0.589 nm	nm
41.	PrT4M.PER	Measure The Zernike Data With Tamis For Monitoring (T4M).			
		Z5 offset	2 nm	Z5: 0.358 nm	Z5: nm
		Z7 offset	2 nm	Z7: 0.123 nm	Z7: nm
		Z8 offset	2 nm	Z8: 0.057 nm	Z8: nm
		Z9 offset	3 nm	Z9: 0192 nm	Z9: nm
42.	I15IllSliUni.PER			3817 ≥ 2400 mW/cm²	mW/cm²
	ASML Setting 1: Annular	NA=.80 σin = .55 σout = .85		≤ 0.8 % 0.69%	%
	ASML Setting 2: Annular	NA=.70 σin = .55 σout = .85		≤ 0.8 %	%
	ASML Setting 1: Quadrupole-30	NA=.80 σin = .55 σout = .85		≤ 1.2 % 0.82%	%
	Headway Setting 1: Annular	NA=.63 σin = .46 σout = .74		No Spec	%
	Headway Setting 2: Annular	NA=.80 σin = .55 σout = .85		No Spec 0.69%	%
	Headway Setting 3: Conventional	NA=.66 σout = .40		No Spec	%
	Headway Setting 4: Conventional	NA=.63 σout = .40		No Spec	

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
	Headway Setting 5: Low Sigma	NA=.58 σin = 0.0 σout: .35		No Spec	_____% _____% _____%
43.	ASML Setting 2: Annular	Measure The Stray Light With The REMA Open And Closed. Control Limit 1.60%		Control Limit: 0.51 _%	Control Limit: _____ _%
44. 2017	Pr5MeaStrSMS.PER	Measure The Stray Light With Samos Cleaning Trigger Max Stray Light At Reference (33 um) block size %) < 3.5%		Block Size: _____%	Block Size:_____%
45.	MeSAlaHeiTlt.ADJ	To Calculate The Off-Axis Unit Best height And Tilt		OAz: 0.142 µm	OAz: _____µm
		OAz total; Correction	0 ± 3 µm	OArx: -8.273 µrad	OArx:_____µrad
		OArx total; Correction	0 ± 50 µrad	OAry: -6.290 µrad	OAry: _____µrad
		OAry total; Correction	0 ± 50 µrad		
		OAz total; New	0 ± 60 µm	New OAz: -6.513µm	New OAz: _____µm
		OArx total; New	0 ± 750 µrad	New OArx -145 µm	New OArx _____µm
		OAry total; New	0 ± 750 µrad	New OArx: -129nm	New OArx:_____nm
		Residual (x)	0 ± 5 nm	Res x: 0.8 nm	Res x: _____nm

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Residual (y)	0 ± 5 nm	Res y: 0.4 nm	Res y: _____ nm
46.	AlaOA_OrdLst.ADJ	Calibrate The Final OA Shifts: (Shift Between Orders) Succeeded: 16 Failed: 0 Max Stdev: < 4 nm Adjusted/Update Taken?:		Succeed 16 Fail 0 Max SD: 3.6 Yes: ✓ No:	Succeed _____ Fail _____ Max SD: _____ Yes: ____ No:
47.	MeSBaShfMc.ADJ	Basic Machine Constants OA Fine		Yes: ✓ No: 5/18	Yes: ____ No: ____
48.	MeSWsMirFla.ADJ	Calibrate The Wafer Stage Mirror Unflatness. X-Mirror offset ≤ 2 nm Y-Mirror offset ≤ 2 nm		X-Mirror: 2.4 nm Y-Mirror: 3.1 nm	X-Mirror: _____ nm Y-Mirror: _____ nm

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
49.	SwsScaDyn.PER	Scanning Dynamic Performance WS-RS/4 MA-X: 5 nm WS-RS/4 MA-Y: 5 nm WS-RS/4 MA-Rz: 0.1 µrad WS-RS/4 MSD-X: 12 nm WS-RS/4 MSD-Y: 12 nm WS-RS/4 MSD-Rz: 0.3 µrad WS MA-Zt: 30 nm WS MSD-Zt: 50 nm	MA-X: 1.3 nm MA-Y: 1.2 nm MA-Rz: 14.8 µrad MSD-X: 7.2 nm MSD-Y: 8.0 nm MSD-Rz 0.11 µrad MA-Zt 10.5 nm MSD-Zt 15.2 nm	MA-X: _____ nm MA-Y: _____ nm MA-Rz: _____ µrad MSD-X: _____ nm MSD-Y: _____ nm MSD-Rz _____ µrad MA-Zt _____ nm MSD-Zt _____ nm
50.	Me5StoMap.ADJ	Scanning Wafer Stage Stone Map Model fit quality; MCC > 0.950 Residuals; Std Dev. Rx < 0.500 µrad Residuals; Std Dev. Ry < 0.500 µrad	MCC: .997 Rx 0.237 µrad Ry: 0.209 µrad	MCC: _____ Rx: _____ µrad Ry: _____ µrad
		Calibrate The Wafer		

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
51.	Me5WsMirFla ADJ2	Stage Fine Mirror Unflatness.		nm	nm
		~~Max~~ Fine Delta x-mirror	0 ± 25 nm	4.7 nm	nm
		Max calculated delta x-mirror	0 ± 25 nm	nm	nm
		~~Max~~ Fine measured delta y-mirror	0 ± 25 nm	-1.1 nm	nm
		Max calculated delta y-mirror	0 ± 25 nm	nm	nm
52.	Me5RsScaTlt ADJ	Determine Reticle Stage Scan Tilt Fine.			
		Wedge linear measured 0 ± 1 urad		0.92 µrad	µrad
		Wedge Linear New 0 ± 90 urad		-34.64 µrad	µrad
		Stage Quadratic measured 0 ± 3.0 nm/cm2		1.96 nm/cm2	nm/cm2
		Stage Quadratic New 0 ± 20 nm/cm2		6.50 nm/cm2	nm/cm2
		Ry Wedge linear measured 0 ± 25 urad/m		7.36 µrad/m	µrad/m
		Ry wedge linear New 0 ± 120 urad/m		60.68 µrad/m	µrad/m
53.	Me5BaSysCor PER	Qualify The System Correction.			
		Mag	0.4 ppm	ppm	ppm

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Rotation	0.4 µRad	µ Rad	µR ad
		Translation X	4 nm	nm	nm
		Translation Y	4 nm	nm	nm
		Image Tilt Rx	4 µRad	µ Rad	µR ad
		Image Tilt Ry	1.5 µRad	µ Rad	µR ad
		Focus	25 nm	nm	nm
54.	Ls8Lam.REP	Replace Halogen Lamp LS (8 Spot Level Sensor)		Yes: ____ No: ____	Yes: ____ No: ____
55.	Ls8MeaGaiWhi.ADJ	Level Sensor Measurement Gain Fine Calibration. Refer To Coach Specifications.		4/21 in spec	
56.	Ls8OffConFin.ADJ	Level Sensor Offset Plane Plates Conversion Factors Fine. P MCC > 0.95 Q MCC > 0.95		P MCC: 0.999 Q MCC: 0.999	P MCC: ____ Q MCC: ____
57.	Ls8QxPxWafInd.ADJ	Calibrate Level Sensor Q Above P and Spot Offsets. Q Above P Standard < 50 nm New Q Above P < 8.5 µm		Standard: 16.2 µm New: 0.041 µm	Standard: ____ µm New: ____ µm
58.	Ls8IsWafOff.ADJ	Determine The Q Above P Image Sensor To Wafer		Yes: ✓ No: ____	Yes: ____

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Offset		No:
59.	Ls8CrsFin.PER	Relative Heights, while varying Tilt Rx Offset (nm) p1a ≤ 60 p2a ≤ 60 p1b ≤ 60 p2b ≤ 60 q1a ≤ 60 q2a ≤ 60 q1b ≤ 60 q2b ≤ 60 p1a-q1a ≤ 50 p2a-q2a ≤ 50 p1b-q1b ≤ 50 p2b-q2b ≤ 50 Tilt Ry Offset (nm) p1a ≤ 60 p2a ≤ 60 p1b ≤ 60 p2b ≤ 60 q1a ≤ 60 q2a ≤ 60 q1b ≤ 60 q2b ≤ 60 p1a-q1a ≤ 50 p2a-q2a ≤ 50 p1b-q1b ≤ 50 p2b-q2b ≤ 50	Tilt Rx Offset (nm) p1a = 41 p2a = 90 p1b = -23 p2b = -50 q1a = 27 q2a = 23 q1b = -13 q2b = -28 p1a-q1a = 14 p2a-q2a = 43 p1b-q1b = 0 p2b-q2b = -23 Tilt Ry Offset (nm) p1a = 30 p2a = 93 p1b = -41 p2b = -65 q1a = 21 q2a = 20 q1b = -29 q2b = -26 p1a-q1a = 9 p2a-q2a = 73 p1b-q1b = -12 p2b-q2b = -39	Yes: ___ No: ___
60.	Ls8FocRep.PER	Total Leveling Repeatability Stddev. TotZ < 0.0167 µm	TotZ 0.0175 µm	TotZ _____ µm
61.	Me5FocCor.ADJ	Perform A Focus Correction With IQC	Yes: ___ No: ___	Yes: ___ No: ___
62.	Me5BaSysCor.PER	Qualify The System Correction.	Mag:	Mag:

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Mag ≤ 0.4 ppm Rotation ≤ 0. 4µrad Translation X ≤ 4 nm Translation Y ≤ 4 nm Image Tilt Rx ≤ 4 µrad Image Tilt Ry ≤ 1.5µrad Focus ≤ 25 nm	_____ppm Rotation: _____µRad X: _____nm Y: _____nm Rx: _____µRad Ry: _____µRad Focus: _____nm	_____ppm Rotation: _____µRad X: _____nm Y: _____nm Rx: _____µRad Ry: _____µRad Focus: _____nm
63.	Me5IqFocLaLADJ	Adjust The Focal Plane, Static- Using Single Energy (Latent) Adjusted Y / N? Best Focus ; Mean 0 ± 30 nm Image Tilt Rx ; Mean 0 ± 6 µrad Image Tilt Ry ; Mean 0 ± 1 µrad	Yes: ✓ No: _____ Focus: 11 nm Rx: 0.779 µrad Ry: 0.774 µrad	Yes: _____ No: _____ Focus: _____nm Rx: _____µrad Ry: _____µrad
64.	Me5StoLnsTltADJ	Stone to Lens Tilt: Delta STOLE Rx / 0 ± 1 µ Delta STOLE Ry / 0 ± 1 µ	Rx: -0.1 µrad Ry: -0.4 µrad	Rx: _____µrad Ry: _____µrad

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
65.	Me5XySetSkw.ABI	Set up XY- Plane and Skew / Scaling Parameters – Static.		Yes: ✓ No: ____	Yes: ____ No: ____
		Adjusted Y / N?	Y/N	DX: 12.6 nm	DX: ____ nm
		Max DX Stdev All	< 20 nm < 7 nm	StdX: 4.4 nm	StdX: ____ nm
		Max DY Stdev All	< 20 nm < 7 nm	DY: 7.5 nm	DY: ____ nm
		Max DX - max RES X	< 10 nm	StdX: 5.2 nm	StdX: ____ nm
		Max DY - max RES Y	< 10 nm	Max DX-max RES X: 4.1 nm	Max DX-max RES X: ____ nm
		Reticle Height correction	0 ± 2 µm	Max DY-max RES Y: 1.7 nm	Max DY-max RES Y: ____ nm
		Skew and rotation	0 ± 0.3 µrad	Ret Height Correction: 0.009 nm	Ret HeightCorrection: ____ nm
		Scaling and Mag	0 ± 0.3 ppm	Skew And Rotation: 0.15 µrad	Skew And Rotation: ____ µrad
		Correction: OA meas. Offset Xx	0 ± 100 nm/m	Scaling and Mag: 0.07 ppm	Scaling and Mag: ____ ppm
		Correction: OA meas. Offset	0 ± 100 nm/m	Xx: 25 nm/m	Xx: ____ nm/m
				Xy: 62 nm /m	Xy: ____ nm /m
				Yx: -10	Yx:

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Xy		−10 nm/m	_____ nm/m
		Correction: OA meas. Offset Yx	0 ± 100 nm/m	Yy: −16 nm/m	Yy: _____ nm/m
		Correction: OA meas. Offset Yy	0 ± 100 nm/m		
66.	Me5XySetDyn.ADJ	Set up XY- Plane and Skew / Scaling Parameters – Dynamic		Yes: ___ No: _____	Yes: _____ No: _____
		Adjusted Y / N?	Y/N	DX: 8.2 nm	DX: _____ nm
		Max DX Stdev All	± 20 nm < 7 nm	StdX: 6.9 nm	StdX: _____ nm
		Max DY Stdev All	< 20 nm < 7 nm	DY: 6.9 nm	DY: _____ nm
		Max DX - max RES X	< 10 nm	StdY: 8.1 nm	StdY: _____ nm
		Max DY - max RES Y	< 10 nm	Max DX-max RES X: 3.4 nm	Max DX-max RES X: _____ nm
		Asymmetric Rotation correction	0 ± 0.5 µrad	Max DY-max RES Y: 0.0 nm	Max DY-max RES Y: _____ nm
		Asymmetric Mag correction	0 ± 0.5µrad	Asym Rot: 0.012	Asym Rot: _____
		Correction: OA meas. Offset Xx: 0 ± 100 nm/m Correction: OA meas. Offset Xy: 0 ± 100 nm/m			

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Item	Reference	Activity	Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Correction: OA meas. Offset Yx: 0 ± 100 nm/m Correction: OA meas. Offset Yy: 0 ± 100 nm/m	Asym Mag: 0.031 Xx: -11 nm/m Xy: 48 nm/m Yx: -45 nm/m Yy: -8 nm/m	Asym Mag: _____ Xx: _____ nm/m Xy: _____ nm/m Yx: _____ nm/m Yy: _____ nm/m
68.	Me5FocDynLat.ADJ	Adjust The Focal Plane, Dynamic – Using Single Adjusted/Update Taken? Height Of Element 1: 0 ± 2µm Best Focus: 0 ± 30nm Image Tilt Ry: 0 ± 1 µrad Energy (Latent)	Yes: ✓ No: ____ Height: -0.0034 µm Focus: 2.8 nm Tilt Ry: -0.542 µrad	Yes: ___ No: ____ Height: _____ µm Focus: _____ nm Tilt Ry: _____ µrad
69.	Mirror Map Matching	3rd (|Mean| + 3Sigma <= 25nm): X=| _____ | X=| _____ | X=| _____ |	1st	2nd
			Y=| _____ | Y=| _____ | Y=| _____ |	
70.	Me5GridVer.PER	Stage Grid Verification Vector 3-sigma XX <15nm Vector 3-sigma XY <15nm	XX: _____ nm	XX: _____ nm

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Item	Reference	Activity		Enter Data / ☑	Enter Data / ☑ If Adjusted/Updated
		Vector 3-sigma YX	<15nm	XY: _____ nm	XY: _____ nm
		Vector 3-sigma YY	<15nm	YX: _____ nm	YX: _____ nm
				YY: _____ nm	YY: _____ nm
71.		Matching of Full Blue Align Scanner to Scanner.		Yes: ____ No: ____	Yes: ____ No: ____
72.		Full System Backup		Yes: ____ No: ____	Yes: ____ No: ____
73.	CsSw_D2dBckADJ	Disk To Disk Back Up		Yes: ____ No: ____	Yes: ____ No: ____
74.		Run Pre chuck cleaning single red flatness test		Yes: ✓ No: ____	
75.		Run chuck cleaning using CLEAR		Yes: _____ No: ____	Yes: _____ No: ____
76.		Run Post chuck cleaning single red flatness test		Yes: _____ No: ____	Yes: ____ No: ____
77		Perform full start up		Yes: ____ No: ____	Yes: ____ No: ____

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